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PATENT

8565-7213 (81839.0077)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Teruaki FUKAMI

Serial No: 09/218,997

Filed: December 22, 1998

For: SILICON WAFER STORAGE
WATER AND SILICON WAFER
STORAGE METHOD

Art Unit: 1744

Examiner: Robert Warden

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PRELIMINARY AMENDMENT

Box RCE

Commissioner for Patents
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Dear Sir:

I hereby certify that this paper and every paper referred to herein is being transmitted via facsimile to recipient at (703) 872-9394 on:

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Date

Further to the filing of an RCE (Request For Continued Examination) for the above-identified application on August 19, 2002, and responsive to the final Office Action dated May 21, 2002, please amend the application as follows:

IN THE CLAIMS:

Rewrite claim 1 as follows:

D1 1. (Three Times Amended) A storage water used for storage of a silicon wafer in water, wherein the storage water is ultra pure water containing Cu at a concentration of 0.01 ppb or less.

Cancel claim 3, without prejudice.

Rewrite claim 4 as follows:

D2 4. (Three Times Amended) A method of storing a silicon wafer in water, comprising the steps of preparing storage water, which is ultra pure water containing Cu at a concentration of 0.01 ppb or less, and storing a silicon wafer in the prepared storage water.